Fabrication of Cu₂Zn(Sn,Si)S₄ Thin Films Using a Two-Step Method for Solar Cell Applications

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To explore Cu₂ZnSnS₄-based materials for solar cell applications, for the first time, $Cu₂Zn(Sn,Si)S₄$ thin films were fabricated using a two-step method that consists of sputtering and post-sulfurization. The films were characterized and then incorporated into solar cells. X-ray diffraction and Raman spectroscopy revealed the formation of $Cu₂Zn(Sn,Si)S₄$ structure with traces of a secondary phase after sulfurization treatments. The degree of sulfurization was enhanced as the temperature was increased. In addition, these techniques revealed that there was no silicon or silicide phase present. The Si/Sn atomic ratio was 0.04-0.10. The thin films exhibited Cu-poor and Zn-rich characteristics and high absorption coefficients. The direct optical band gap of the thin films ranged between 1.42 and 1.52 eV. Heterojunction solar cells (glass/Mo/ Cu2Zn(Sn,Si)S4/CdS/i-ZnO/ZnO:Al/Al) were fabricated and exhibited the highest conversion efficiency of 0.427%. This study showed the feasibilities of fabricating $Cu₂Zn(Sn,Si)S₄$ thin films by a two-step method and using $Cu₂Zn(Sn,Si)S₄$ thin films as an absorber layer within a solar cell.

Keywords: Cu₂Zn(Sn,Si)S₄, magnetron sputtering, sulfurization, thin films, solar cells

1. INTRODUCTION

 $Cu₂ZnSnS₄$ thin films show potential as the next generation of absorber materials for solar cell applications.^[1-3] They have absorption coefficients above 1×10^4 cm⁻¹ in the visible region, $[4-7]$ have a band gap that is suitable for singlejunction solar cells (~1.5 eV),^[1,5,8] show p-type conductivity, and are environmentally friendly.

Recent attention has focused on the semiconducting properties of $Cu₂Zn(Sn,Si)S₄$, which are similar to those of $Cu₂ZnSnS₄.^[9-11]$ For $Cu₂ZnSnS₄, Sn loss occurs at high$ temperature owing to the volatility of $SnS^[12,13] Cu₂Zn(Sn,Si)S₄$ is formed by the partial substitution of Sn in $Cu₂ZnSnS₄$ with Si. This substitution is expected to inhibit Sn loss. To date,

only single crystals of Cu₂Zn(Sn,Si)S₄ or Cu₂ZnSiSe₄ have been investigated.^[9-11,14] The effect of substituting Sn with Si has also been studied.^[11] Although the structure and properties of $Cu₂Zn(Sn,Si)S₄$ single crystals have been investigated, this material will be incorporated into solar cells as a thin film. To the best of our knowledge, the $Cu₂Zn(Sn,Si)S₄$ thin films have not been reported. Therefore, an understanding of the structure, properties, and fabrication methods of $Cu₂Zn(Sn,Si)S₄$ thin films and solar cells is critical.

In this work, we report a two-step method for the fabrication of $Cu₂Zn(Sn,Si)S₄$ thin films on soda-lime glass substrates. This involved the deposition of a Zn/Sn/Si/Cu stacked precursor followed by sulfurization treatment. Sulfurization treatment converted the stacked precursor into the desired $Cu₂Zn(Sn,Si)S₄$ structure. The structural, compositional, morphological, and optical properties of the thin

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films were examined after sulfurization treatment at different temperatures. $Cu₂Zn(Sn,Si)S₄$ thin films were then incorporated as an absorber layer in solar cells.

2. EXPERIMENTAL PROCEDURE

Soda-lime glass was used as a substrate (2 cm \times 1 cm \times 1 mm). The glass substrates were cleaned using a standard process and then loaded into a magnetron sputtering chamber. The source materials used for deposition were Zn, Sn, Si, and Cu targets. The base and working pressures were 5×10^{-4} Pa and 0.5 Pa, respectively. During deposition, pure argon was introduced into the chamber at a flow rate of 20 mL/min. Zn, Sn, Si, and Cu were successively sputtered onto the glass substrates to form the Zn/Sn/Si/Cu stacked precursors. Zn and Cu were the bottom and top layers, respectively. Zn and Cu were sputtered using direct-current mode, and Sn and Si were deposited using radio frequency sputtering. The sputtering parameters for each layer are listed in Table 1.

After sputtering, the precursors were transferred into a tubular furnace for sulfurization treatment. Sulfur powder (99.95%, 1 g) was used as a source material. The sulfur powder and precursors were placed in a capped quartz boat positioned in the center of the tubular furnace. A N_2+S atmosphere was used for sulfurization with a N_2 flow rate of 250 mL/min. The furnace temperature as a function of time is shown in Fig. 1. The sulfurization treatment was performed

Table 1. The sputtering parameters for Zn/Sn/Si/Cu stacked precursors.

| Target | Sputtering power (W) Sputtering time (s) | |
|--------|--|------|
| Zn | 300 | 16 |
| Sn | 50 | 1140 |
| Si | 100 | 120 |
| ∴u | 40 | 270 |

Fig. 1. Schematic of the temperature during sulfurization treatments.

in two steps: we first preheated the samples to 150 °C, and then heated them to the target temperature (500 \degree C, 540 \degree C, and 580 °C) for 30 min. The samples were then allowed to cool to ambient temperature in the tubular furnace.

The $Cu₂Zn(Sn,Si)S₄$ heterojunction solar cells had a structure consisting of glass/Mo $(1 \mu m)/Cu₂Zn$ $(Sn,Si)S₄/$ CdS (50 nm)/i-ZnO (50 nm)/ZnO:Al (800 nm)/Al (500 nm). A back contact Mo thin film was sputtered on the glass substrate. The $Cu₂Zn(Sn,Si)S₄$ absorber layer was then deposited on the Mo layer using the two-step method described previously. A CdS buffer layer was fabricated using chemical bath deposition followed by i-ZnO and ZnO:Al window layers that were deposited by magnetron sputtering. Finally, the Al front contact was sputtered in a finger pattern via mask.

The structural properties of the $Cu₂Zn(Sn,Si)S₄$ thin films were characterized using x-ray diffraction (XRD) (Rigaku D/MAX-Ultima IV, Cu-k α radiation, $\lambda = 0.154$ nm) and Raman spectroscopy (HORIBA Jobin Yvon, LabRAM HR800, $\lambda = 633$ nm). Field emission scanning electron microscopy (FESEM) (Hitachi SU8010) was used to observe the surface and cross-sectional morphologies of the $Cu₂Zn(Sn,Si)S₄$ thin films. The optical properties of the $Cu₂Zn(Sn.Si)S₄$ thin films were examined using an ultravioletvisible spectrophotometer (Pgeneral, T6).

The elemental compositions of the $Cu₂Zn(Sn,Si)S₄$ thin films were measured using energy dispersive spectrometer (EDS). The substrate of the measured $Cu₂Zn(Sn,Si)S₄$ thin films was Mo foil because the Si in the soda-lime glass substrate would contribute to the measured results of the film's composition. The sputtering and sulfurization conditions used to fabricate the $Cu₂Zn(Sn,Si)S₄$ thin films on the Mo foil were identical to those used with the sodalime glass substrates.

The photovoltaic performance of the $Cu₂Zn(Sn,Si)S₄$ thin film solar cells under simulated AM1.5 illumination was measured using a solar simulator and a digital source meter (Keithley 2400).

3. RESULTS AND DISCUSSION

XRD spectra of the thin films that were sulfurized at different temperatures are shown in Fig. 2. The thin film that was sulfurized at 500 °C exhibited peak characteristics of (112), (220), and (312) planes, which were typically observed in $Cu₂Zn(Sn,Si)S₄$ ^[10,11] When the sulfurization temperature was increased to 540 °C, an additional weak peak was identified at approximately 33 °, which was attributed to the (200) plane of $Cu₂Zn(Sn,Si)S₄$. The XRD spectrum of the thin film sulfurized at 580 °C contained a new peak characteristic of the (101) plane. All $Cu₂Zn(Sn,Si)S₄$ thin films had polycrystalline structures. The preferred orientation of the $Cu₂Zn(Sn,Si)S₄$ thin films was along the

Fig. 2. The XRD spectra of $Cu₂Zn(Sn,Si)S₄$ thin films sulfurized at different temperatures.

Fig. 3. The changes of intensity and FWHM of the preferred (112) peak with sulfurization temperature.

(112) plane, which was consistent with the reports of $Cu₂ZnSnS₄$ thin films^[15-18] and $Cu₂Zn(Sn,Si)S₄$ single crystals.[10,11] XRD peak characteristics of silicon or silicides were not present in any of the XRD spectra.

The intensity and full width at half maximum (FWHM) of the peaks that correspond to the preferred (112) plane at different sulfurization temperatures are shown in Fig. 3. The peak intensity increased consistently with increasing sulfurization temperature, while the FWHM decreased. The peak intensity of the thin film sulfurized at 580 °C was 1.47 times that of the thin film sulfurized at 500 °C. The position of the (112) peak did not change with the sulfurization temperature, which indicated that the lattice constant of the $Cu₂Zn(Sn,Si)S₄$ thin films was independent of that temperature. The grain size (D) of a $Cu₂Zn(Sn,Si)S₄$ thin film is calculated using the Debye-Scherrer equation:

$$
D = \frac{0.89 \lambda}{\beta \cos \theta},
$$

Fig. 4. The Raman spectra of Cu₂Zn(Sn,Si)S₄ thin films sulfurized at different temperatures.

where λ , β , and θ are the wavelength of Cu-k α radiation, the FWHM of the (112) peak, and the diffraction angle of the (112) peak, respectively. The values of D for the thin films that were sulfurized at 500 °C, 540 °C, and 580 °C were 34.0 nm, 36.2 nm, and 40.7 nm, respectively. These results revealed that the crystallinity of the thin films was enhanced as the sulfurization temperature increased, which was in agreement with literature reports for $Cu₂ZnSnS₄.$ ^[5,19] The higher energies associated with higher temperatures enhanced the degree of sulfurization reaction, which resulted in increased crystallinity within the thin films.

As the XRD peaks (Fig. 2) may have originated from secondary phases of $Cu₂Zn(Sn,Si)S₄$, we used Raman scattering measurements to further characterize the phase structure of the thin films (Fig. 4). The Raman peaks observed in the spectra of the thin films $(264 \text{ cm}^{-1}, 288 \text{ cm}^{-1},$ 302 cm⁻¹, 338 cm⁻¹, and 367 cm⁻¹) had been previously assigned to the $Cu₂ZnSnS₄$ structure,^[20] which indicated that the Cu2ZnSnS4 phase had formed in all of the thin films. The strongest peak located at 338 cm⁻¹ was attributed to the A₁ mode of $Cu₂ZnSnS₄$, which was consistent with $Cu₂ZnSnS₄$ thin films.[21-23] Peak characteristics of silicon and related silicides were not detected in the Raman scattering spectra. The thin film that was sulfurized at 580 °C contained a secondary phase as evidenced by a peak characteristic of ZnS. Therefore, the phase structure of this thin film consisted of $Cu₂Zn(Sn,Si)S₄$ with traces of a secondary ZnS phase, which may have resulted from the decomposition of $Cu₂Zn(Sn.Si)S₄$ at the high sulfurization temperature used. As the sulfurization temperature increased, the Raman peak characteristics of Cu₂ZnSnS₄ increased and narrowed significantly, particularly the peaks located at 338 cm^{-1} and 367 cm⁻¹. This result indicated that the thin films were more crystalline, which was consistent with the XRD results.

| Sulfurization temperature $(^{\circ}C)$ | Cu (at.%) | Zn (at.%) | Sn (at.%) | Si (at.%) | S (at.%) | $Cu/(Zn+Sn+Si)$ | $Zn/(Sn+Si)$ | Si/Sn |
|--|-------------|--------------------|-------------|-------------|------------|-----------------|--------------|-----------|
| 500 | 15.95 | 19.92 | 9.08 | 0.89 | 54.16 | 0.53 | 2.00 | 0.10 |
| 540 | 16.54 | 21.41 | 8.79 | 0.32 | 52.94 | 0.54 | 2.35 | 0.04 |
| 580 | 17.09 | 19.90 | 9.86 | 0.67 | 52.48 | 0.56 | . 89 | $_{0.07}$ |

Table 2. The compositional properties of the prepared thin films.

The XRD and Raman results indicated that the stacked precursor layers (Zn/Sn/Si/Cu) interdiffused and reacted with sulfur during the sulfurization treatment, which led to the $Cu₂Zn(Sn,Si)S₄$ structure. The Si layer in the stacked precursor did not impede formation of the Cu₂ZnSnS₄ phase. The degrees of sulfurization and crystallinity of thin films depended on the sulfurization temperature. The sulfurization temperature was not increased further because of the potential for thermal instability of the soda-lime glass at higher temperatures. These results showed that $Cu₂Zn(Sn,Si)S₄$ thin films can be prepared successfully using the two-step method described.

The elemental composition of thin films fabricated on Mo foil substrates, including Cu, Zn, Sn, Si, and S, and the atomic ratios of Cu/(Zn+Sn+Si), Zn/(Sn+Si), and Si/Sn, are shown in Table 2. Mo was ignored during the EDS measurements. The S ratio in all of the thin films was close to the standard value of 50%. The ratios of Cu and Zn exhibited a degree of non-stoichiometry. All thin films were Cu-poor and Zn-rich, which was a requirement for solar cell applications using $Cu₂ZnSnS₄.$ ^[24-26] However, the values of Cu/(Zn+Sn+Si) and Zn/(Sn+Si) deviated from the optimum values reported for $Cu₂ZnSnS₄.^[24-26]$ Therefore, the atomic percentages of Cu and Zn within the films need to be optimized in future work. The values of the Si/Sn ratio (0.04- 0.10) indicated the substitution of Sn by Si.

Surface SEM images of the thin films sulfurized at 500 °C, 540 °C, and 580 °C are shown in Fig. 5. The surface of the thin film sulfurized at 500 °C (Fig. 5(a)) was inhomogeneous, and the grainy morphology was insignificant. Meanwhile, several voids appeared on the surface. The film that was sulfurized at 540 °C exhibited a slightly enlarged grain size. However, the distribution of the grains was still inhomogeneous. When the sulfurization temperature was increased to 580 °C, the grainy morphology was observed clearly; the grain size on the surface had increased significantly.

The cross-sectional SEM images of the $Cu₂Zn(Sn,Si)S₄$ thin films also exhibited grainy morphologies (Fig. 6). The grains enlarged with increasing sulfurization temperature. However, the voids also increased when the sulfurization temperature was increased to 580 °C, which was attributed to the decomposition of the $Cu₂Zn(Sn,Si)S₄$ structure. The thicknesses of the $Cu₂Zn(Sn,Si)S₄$ thin films, determined from the cross-sectional images, were $0.75 \mu m$, 1 μ m, and 1.25 µm when sulfurized at 500 °C, 540 °C, and 580 °C,

Fig. 5. The surface SEM images of $Cu₂Zn(Sn,Si)S₄$ thin films sulfurized at (a) $500 \,^{\circ}$ C, (b) $540 \,^{\circ}$ C, and (c) $580 \,^{\circ}$ C.

respectively. The increased thickness suggested that the degree of sulfurization enhanced with increasing temperature.

The transmittance of the thin films from 400 nm to 1000 nm is shown in Fig. 7. The transmittance in the visible region was lower than 8% for all films, revealing high absorption of $Cu₂Zn(Sn,Si)S₄$ thin films. The absorption coefficient (α) of a thin film is provided by the following equation:

Fig. 6. The cross-sectional SEM images of Cu₂Zn(Sn,Si)S₄ thin films sulfurized at (a) 500 °C, (b) 540 °C, and (c) 580 °C.

Fig. 7. The transmittance spectra of $Cu₂Zn(Sn,Si)S₄$ thin films.

$$
\alpha = \left(\frac{1}{d}\right) \ln\left(\frac{1}{T}\right),\,
$$

where d and T are the thickness and transmittance of the thin film, respectively. The relationship between $(\alpha h v)^2$ and $h v$ for the thin films, where $h\nu$ is the photon energy, is shown in Fig. 8. A linear relationship existed in the high-energy region. The linear lines were extrapolated to the $h\nu$ axis (depicted by dashed lines) to give an estimation of the direct optical band gaps of the thin films (the intercept of the $h\nu$ axis). The direct optical band gaps for the thin films that were sulfurized at 500 °C, 540 °C, and 580 °C were 1.52 eV, 1.49 eV, and 1.42 eV, respectively. These values were similar to the reported band gaps for $Cu₂ZnSn₄$ and $Cu₂ZnSn₄$ $Si)S₄$ ^[5,8,9] At lower sulfurization temperatures, the reduced grain size led to an increased optical band gap because of the quantum confinement effect. Above the optical band gap, the absorption coefficients of the $Cu₂Zn(Sn,Si)S₄$ thin films were on the order of 10^4 cm⁻¹, which was suitable for an absorber material in solar cells.

The current density-voltage $(J-V)$ characteristics of the

²- $h\nu$ curves of Cu₂Zn(Sn,Si)S₄ thin films.

Fig. 9. The $J-V$ characteristics of Cu₂Zn(Sn,Si)S₄ thin film solar cells when the absorbers sulfurized at different temperatures.

 $Cu₂Zn(Sn,Si)S₄$ thin film solar cells under AM1.5 illumination are shown in Fig. 9. The open-circuit voltage (V_{oc}) , short-

| Sulfurization temperature $(^{\circ}C)$ | V_{ac} V) | J_{sc} (mA/cm ²) | FF | $\frac{1}{2}$ |
|--|----------------|-----------------------------------|------|---------------|
| 500 | 0.08 | 2.58 | 0.25 | 0.051 |
| 540 | 0.14 | 3.42 | 0.29 | 0.139 |
| 580 | 0.27 | 4.16 | 0.38 | 0.427 |

Table 3. The photovoltaic properties of $Cu₂Zn(Sn,Si)S₄$ thin film solar cells for different sulfurization temperatures.

circuit current density (J_{sc}) , fill factor (FF), and conversion efficiency (η) of solar cells were obtained from the *J-V* curves and are given in Table 3. The photovoltaic properties of Cu2Zn(Sn,Si)S4 solar cells improved with the increasing sulfurization temperature, which was due to the enhanced crystallinity and thickness of Cu₂Zn(Sn,Si)S₄ absorber. However, the highest conversion efficiency of solar cells was only 0.427%, which was lower than that of $Cu₂ZnSnS₄$ thin film solar cells^[1,2,4,16,18,25] and was limited by the low values of V_{oc} , J_{sc} , and FF. The reciprocal of the slope of the J- V curve at the short-circuit current point gave a shunt resistance of 336 Ω ·cm² when Cu₂Zn(Sn,Si)S₄ sulfurized at 580 °C. The low values of the shunt resistance led to low conversion efficiency. The voids that were revealed from the cross-sectional SEM images may have produced parasitic current paths, which resulted in the reduction of the shunt resistance. Although the $Cu₂Zn(Sn,Si)S₄$ thin film solar cells exhibited inferior photovoltaic performances, this work showed that $Cu₂Zn(Sn,Si)S₄$ thin films can be successfully incorporated and used as an absorber layer within solar cells.

4. CONCLUSIONS

Zn/Sn/Si/Cu-layered stacks were sputtered onto soda-lime glass substrates as precursor films, which were then subjected to sulfurization. The successful fabrication of the $Cu₂Zn(Sn,Si)S₄$ thin films using a two-step method involving magnetron sputtering and post-sulfurization was confirmed using a combination of XRD, Raman spectroscopy, and SEM. The preferred orientation of the $Cu₂Zn(Sn,Si)S₄$ thin films was along the (112) plane. The XRD, Raman, and SEM results revealed that the degrees of sulfurization and crystallinity within the $Cu₂Zn(Sn,Si)S₄$ thin films were enhanced at higher sulfurization temperatures. The composition of thin films was Cu-poor and Zn-rich, with an atomic ratio of Si/Sn that varied from 0.04 to 0.10. The direct optical band gap ranged between 1.42 and 1.52 eV. Heterojunction solar cells were fabricated (glass/Mo/Cu₂Zn(Sn,Si)S₄/CdS/i-ZnO/ZnO:Al/Al) that exhibited the highest conversion efficiency of 0.427%. Further work is required to optimize the prepared conditions for improving the properties of the $Cu₂Zn(Sn,Si)S₄ solar cells that incorporate these films.$

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